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Enton: A COMPOSITION OF 1 6 2005 W	TION FOR ANTIREFLECTIVE (	COATING AND METHOD I	FOR FORMING SAME
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## PATENT ABSTRACTS OF JAPAN

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(21)Application number: 06-049931 (71)Applicant: JAPAN SYNTHETIC RUBBER

CO LTD

(22)Date of filing: 24.02.1994 (72)Inventor: SHIMA MOTOYUKI

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(54) BASE-INTERCEPTING ANTIREFLECTION FILM AND RESIST PATTERN FORMING METHOD

(57)Abstract:

PURPOSE: To improve resolution, developability, pattern formation and the efficiency of application by containing a specified copolymer and/or salt, and fluoroalkyl solfonic acid and/or fluoroalkyl carboxylic acid.

CONSTITUTION: A base-intercepting antireflection film contains a copolymer having one kind of a repeat unit expressed by the formula I and one kind of a repeat unit expressed by the formula II and/or fluoroalkyl solfonic acid having a fluoroalkyl group with the carbon number of 5-15 and/or fluoroalkyl carboxylic acid having a fluoroalkyl group with the carbon number of 5-15. In the formula I, R1 indicates a hydrogen atom or an organic group, Rf indicates a fluoroalkyl group, and A indicates a hydrogen atom or an organic group, Rf indicates a fluoroalkyl group, and A

oup or a fluoroalkylene group. Thus, in the a basic material in the atmosphere can be wave effect can be reduced enough.

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